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PATENT & TRADEMARK OFFICE

TSMC-02-420

April 2, 2004

To: Commissioner for Patents
P.O.Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: Serial No. 10/757,204 01/14/04

Chih-Ming Ke et al.

A NEW APPROACH TO IMPROVE ELLIPSOMETER MODELING ACCURACY FOR SOLVING MATERIAL OPTICAL CONSTANTS N & K

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation In An Application.

The following Patents and/or Publications are submitted to comply with the duty of disclosure under CFR 1.97-1.99 and 37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on April 12, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date 4/12/04

The following four U.S. Patents describe a composite optical measurement system that involves internal calibration as well as n and k measurements of single layer or multi-layer film stacks:

1) U.S. Patent 5,798,837 to Aspnes et al., "Thin Film Optical Measurement System and Method with Calibrating Ellipsometer".
2) U.S. Patent 6,304,326 to Aspnes et al., "Thin Film Optical Measurement System and Method with Calibrating Ellipsometer."
3) U.S. Patent 6,411,385 to Aspnes et al., "Thin Film Optical Measurement System and Method with Calibrating Ellipsometer."
4) U.S. Patent 6,417,921 to Rosencwaig et al., "Apparatus for Analyzing Multi-Layer Thin film Stacks on Semiconductors."

U.S. Patent 6,057,928 to Li et al., "Free-Space Time-Domain Method for Measuring Thin Film Dielectric Properties," describes a non-contact method for determining the index of refraction or dielectric constant of a thin polymer film on a silicon substrate in the GHz to THz frequenacy range.

Sincerely,

Stephen B. Ackerman,
Reg. No. 37761

Form PTO-1449

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

OIPE SC125 APR 15 2004 PATENT & TRADEMARK OFFICE

Docket Number (Optional)	Application Number
TSMC-02-420	10/757,204
Applicant: Chih-Ming Ke et al.	
Filing Date: 01/14/04	Group Art Unit:

U. S. PATENT DOCUMENTS

	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
	5,798,837	8/25/98	Aspnes et al.	356	369	7/11/97
	6,304,326	10/16/01	Aspnes et al.	356	369	2/8/99
	6,411,385	6/25/02	Aspnes et al.	356	369	6/21/01
	6,417,921	7/9/02	Rosencwaig et al.	356	369	6/13/01
	6,057,928	5/2/00	Li et al.	356	445	6/15/99

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation YES	Translation NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner	Date Considered

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant